

# Modeling, Validation and Control of Manufacturing Systems

Erjen Lefeber

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Information and Material Flows in Complex Networks

Introduction to  $\chi$ 

From real fab to DEM

Effective process times

Control Framework

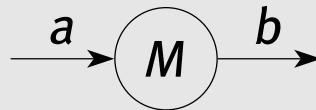
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## Machine



```
proc  $M(a : ?\text{lot}, b : !\text{lot}, t_e, c_e^2 : \text{real}) =$   
  |[  $u : \rightarrow \text{real}, x : \text{lot}$   
    |  $u := \Gamma(t_e, c_e^2)$   
    ;  $*[\text{true} \rightarrow a?x; \Delta\sigma u; b!x]$   
  ]|
```

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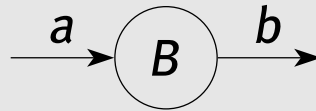
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## Buffer



```
proc B(a : ?lot, b : !lot) =  
  |[ x : lot, xs : lot*  
    | xs := []  
    ; *[ true;      a?x      → xs := xs ++ [x]  
        || len(xs) > 0; b!hd(xs) → xs := tl(xs)  
    ]  
  ]|
```

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## Generator and Exit

type lot = real

proc  $G(a : !\text{lot}, t_a : \text{real}) = [| \text{*[ true} \rightarrow a!\tau; \Delta t_a ] |]$

proc  $E(a : ?\text{lot}) =$

$| [ x : \text{lot}$

$| \text{*[ true} \rightarrow a?x; !\text{"Flow time: ", } x - \tau, \text{"\ n"} ]$

$| ]$

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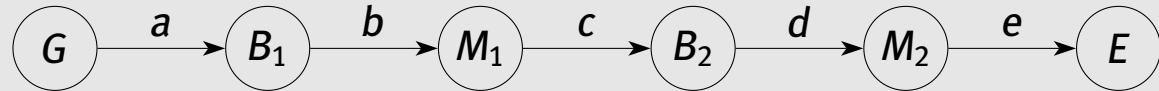
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## Overall model



clus  $F() =$

$[[ a, b, c, d, e : -\text{lot}$

$| G(a, 3.0)$

$|| B(a, b) || M(b, c, 1.0, 1.0)$

$|| B(c, d) || M(d, e, 2.0, 1.0)$

$|| E(e)$

$]]$

xper =  $[[ F() ]]$

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## Discrete Event Modeling of a real factory

- raw process time  $t_0$  and  $c_0$
- setups  $t_s$  and  $c_s$
- TBF  $t_f$  and  $c_f$ , TTR  $t_r$  and  $c_r$
- operator delays
- rework
- ... (!)

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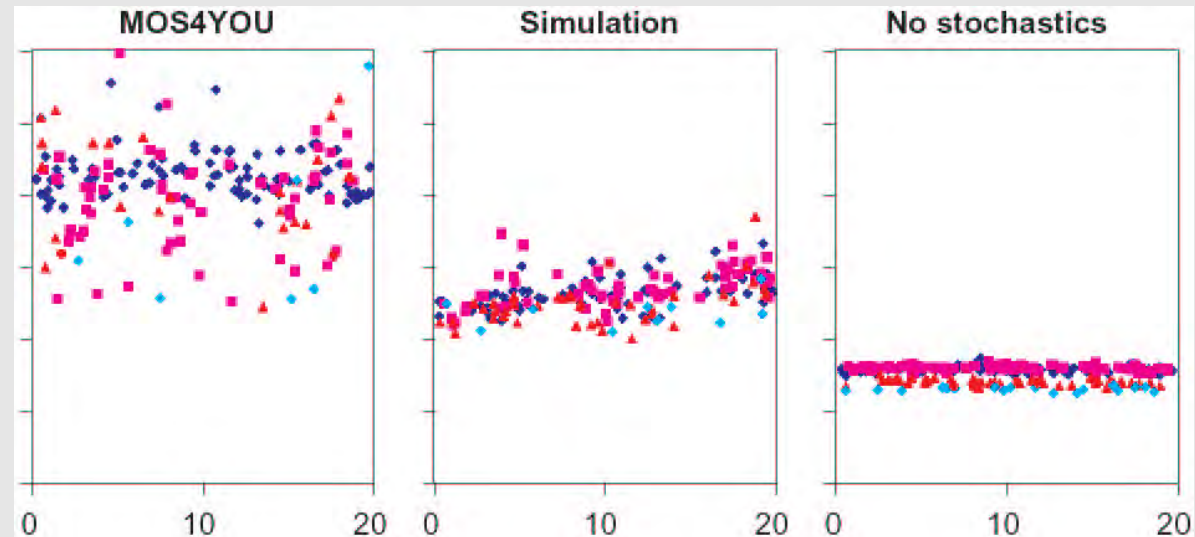
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## Results



- smaller mean flow time
- smaller variance flow time

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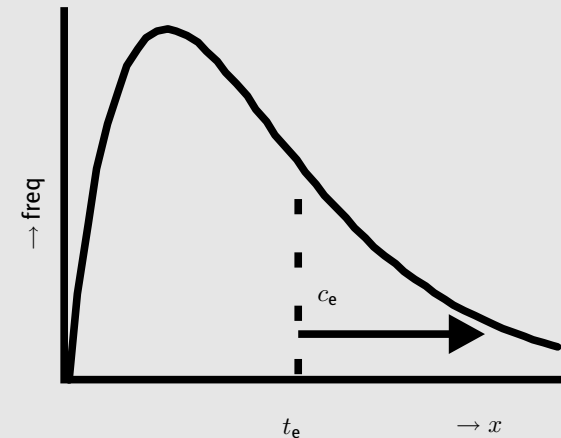
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## The effective process time method

- raw process time  $t_0$  and  $c_0$
- setups  $t_s$  and  $c_s$
- TBF  $t_f$  and  $c_f$ , TTR  $t_r$  and  $c_r$
- operator delays
- rework
- ... (!)

Idea:

Combine all disturbances in one single EPT probability density function





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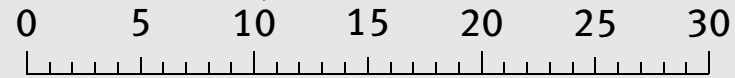
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## Effective process times



Legend

Setup

Processing

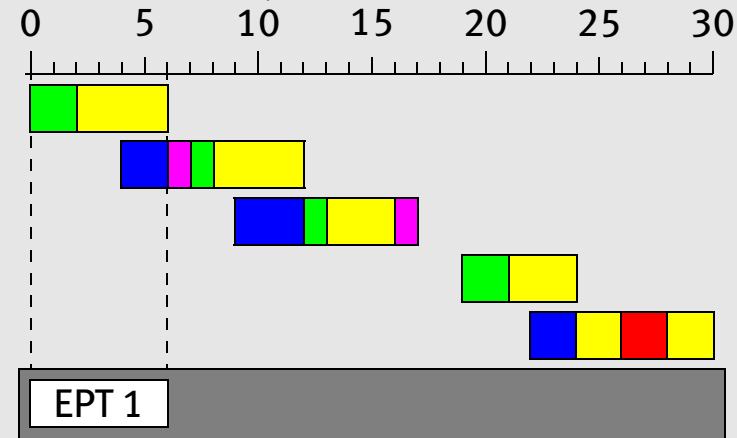
Queueing

Waiting for operator

Machine breakdown

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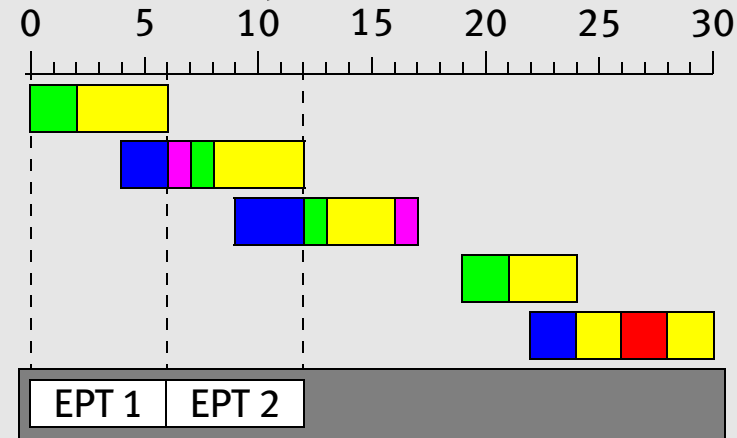


### Legend

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- Queueing
- Waiting for operator
- Machine breakdown

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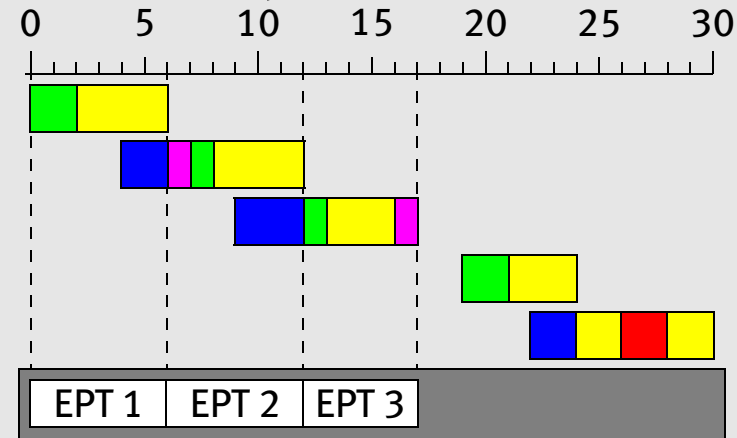


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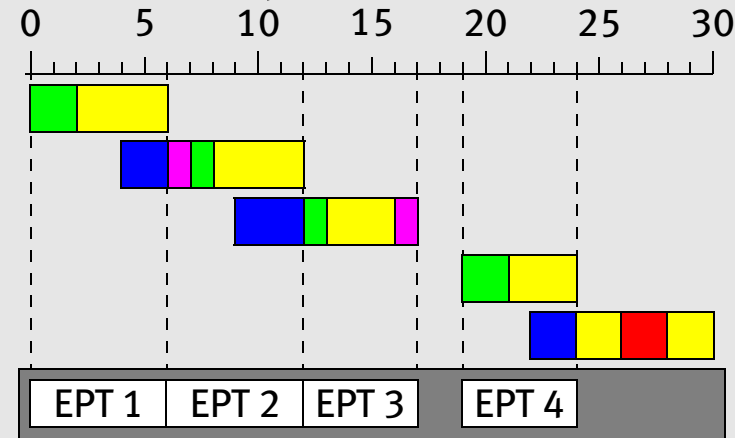


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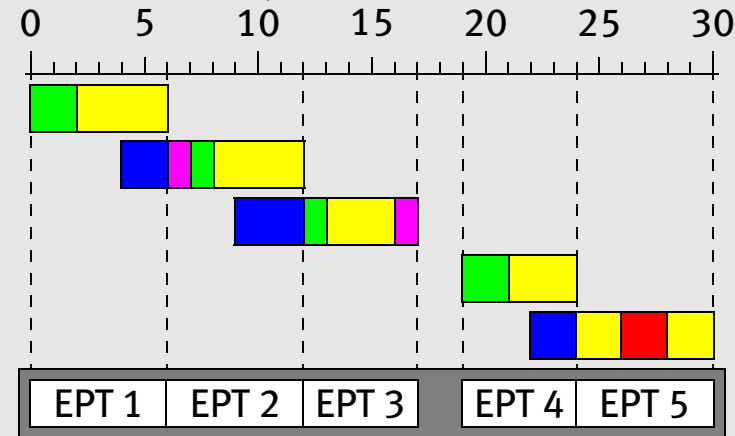


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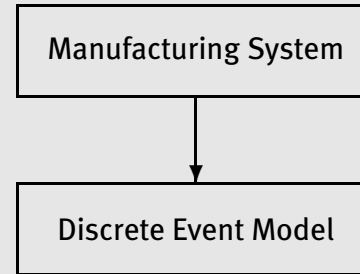
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## Control Framework

Manufacturing System

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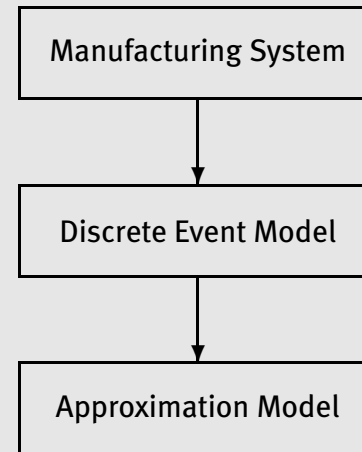
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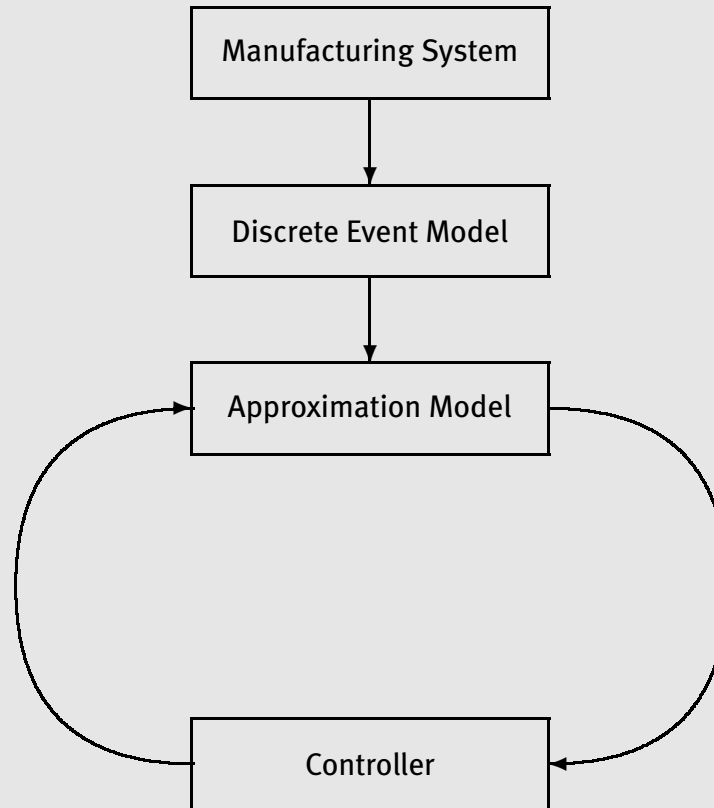
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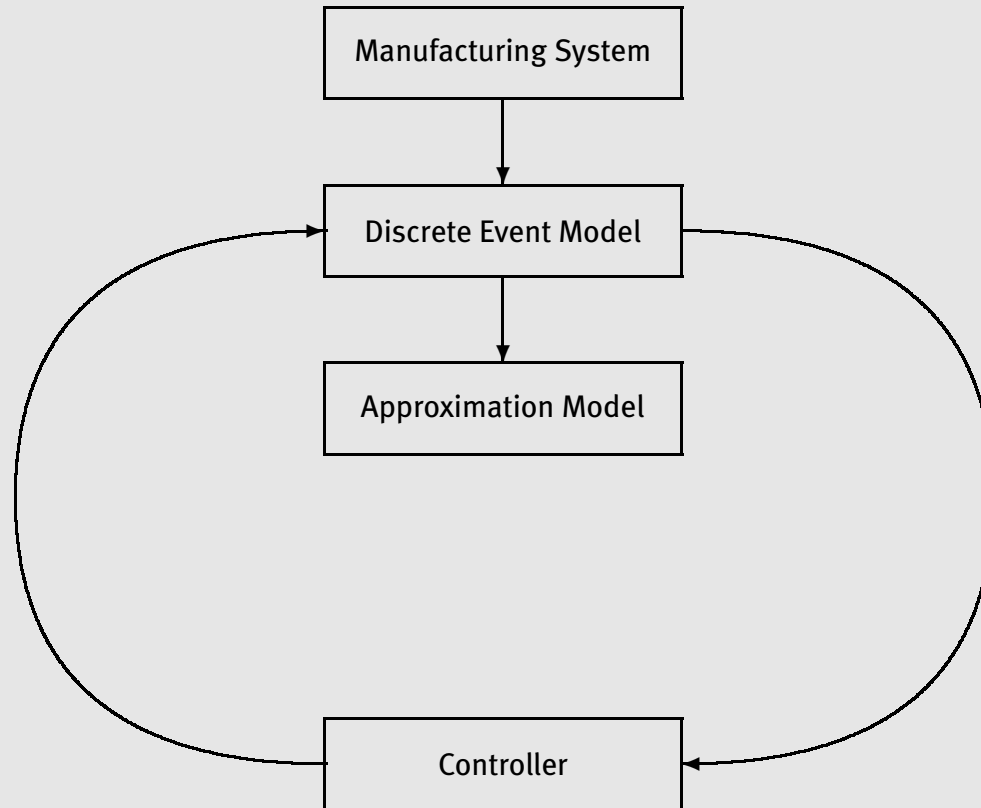
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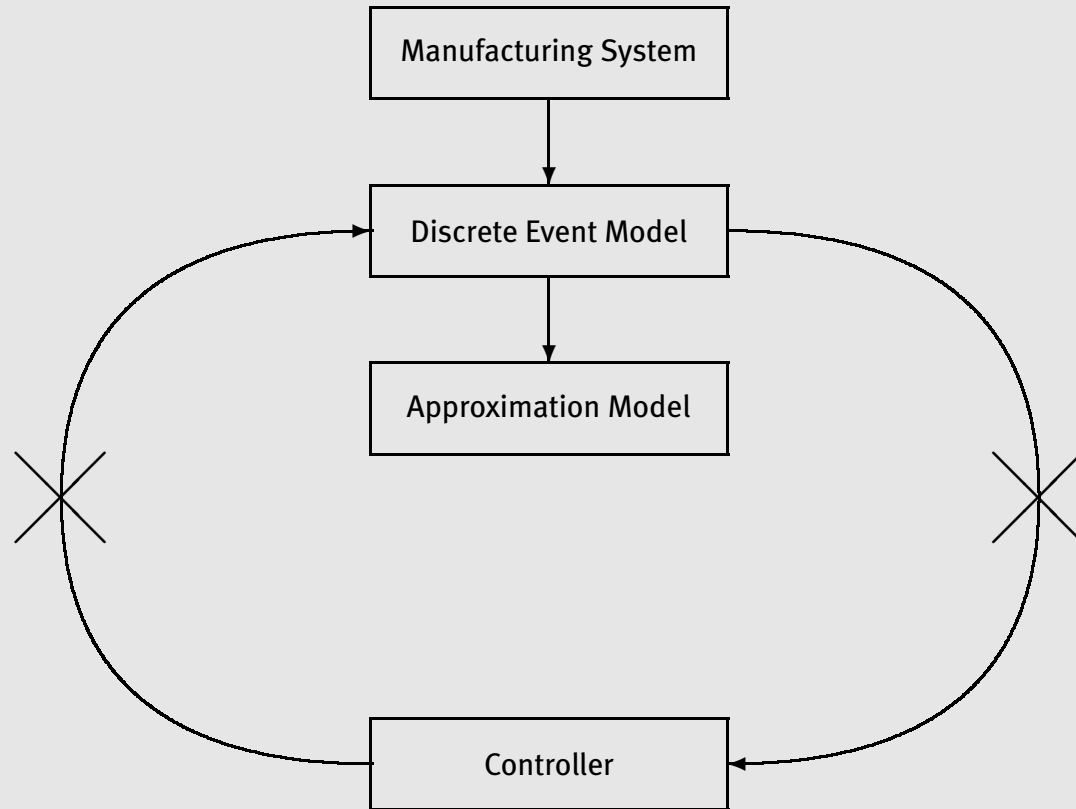
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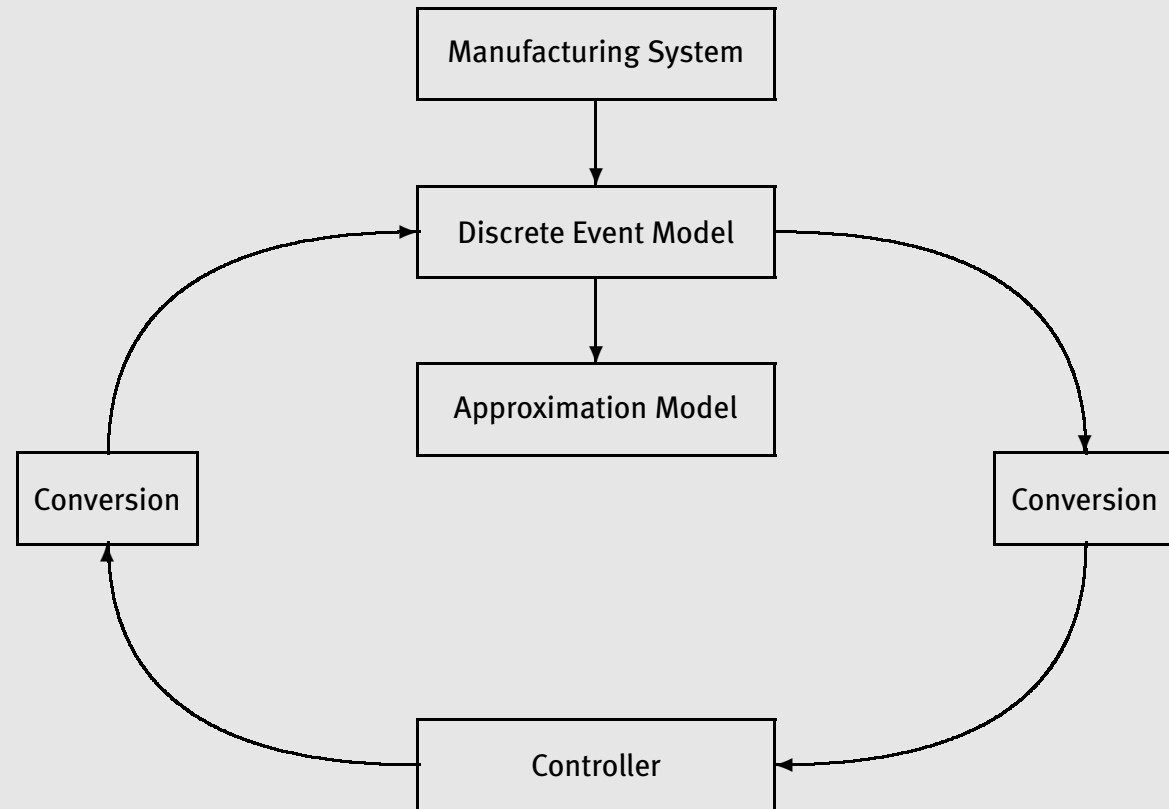
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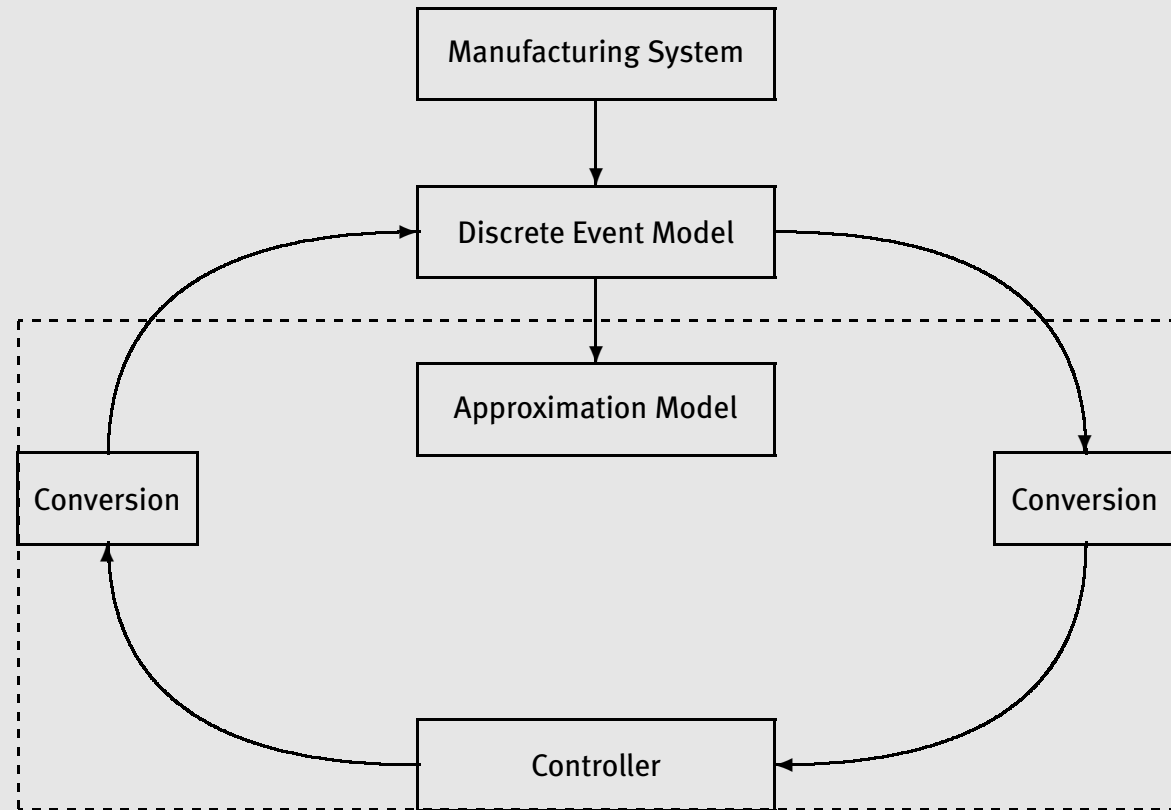
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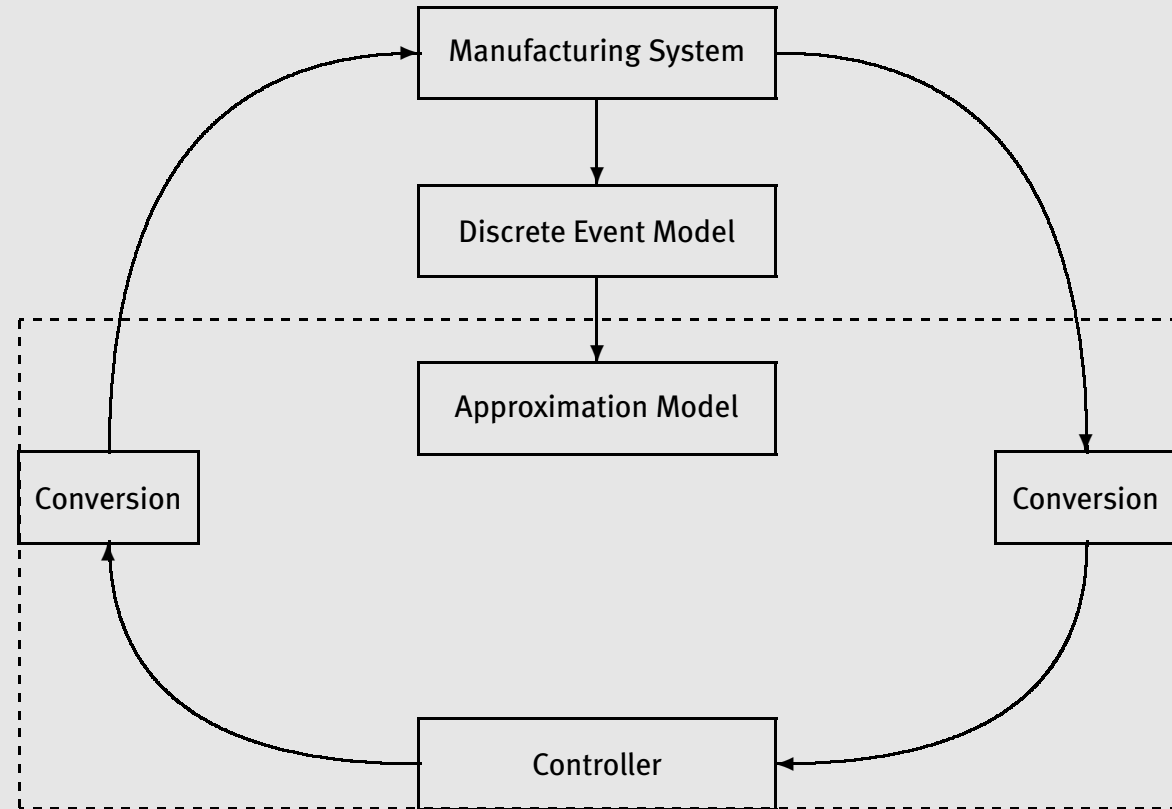
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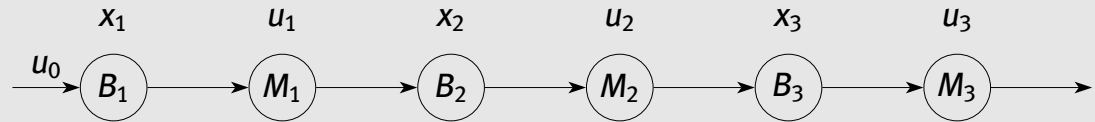
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## Approximation model



$$x_1(k+1) = x_1(k) + u_0(k) - u_1(k)$$

$$x_2(k+1) = x_2(k) + u_1(k) - u_2(k)$$

$$x_3(k+1) = x_3(k) + u_2(k) - u_3(k)$$

or

$$\dot{x}_1(t) = u_0(t) - u_1(t)$$

$$\dot{x}_1(t) = u_0(t) - u_1(t)$$

$$\dot{x}_2(t) = u_1(t) - u_2(t)$$

$$\text{or } \dot{x}_2(t) = u_1(t - \tau_1) - u_2(t)$$

$$\dot{x}_3(t) = u_2(t) - u_3(t)$$

$$\dot{x}_3(t) = u_2(t - \tau_2) - u_3(t)$$



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## Modeling manufacturing flow

- density  $\rho(x, t)$ ,
- speed  $v(x, t)$ ,
- flow  $u(x, t) = \rho(x, t)v(x, t)$ ,
- Conservation of mass:  $\frac{\partial \rho}{\partial t}(x, t) + \frac{\partial \rho v}{\partial x}(x, t) = 0$ .
- Boundary condition:  $u(0, t) = \lambda(t)$

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## Modeling manufacturing flow

Armbruster, Marthaler, Ringhofer (2002):

- Single queue:  $\frac{1}{v(x,t)} = \frac{1}{\mu} (1 + \int_0^1 \rho(s,t) ds)$
- Single queue:  $\frac{\partial \rho v}{\partial t}(x,t) + \frac{\partial \rho v^2}{\partial x}(x,t) = 0$

$$\rho v^2(0,t) = \frac{\mu \cdot \rho v(0,t)}{1 + \int_0^1 \rho(s,t) ds}$$

- Re-entrant:  $v(x,t) = v_0 \left( 1 - \frac{\int_0^1 \rho(s,t) ds}{W_{\max}} \right)$
- Re-entrant:  $\frac{\partial \rho v}{\partial t}(x,t) + \frac{\partial \rho v^2}{\partial x}(x,t) = 0$

$$\rho v^2(0,t) = \rho v(0,t) \cdot v_0 \left( 1 - \frac{\int_0^1 \rho(s,t) ds}{W_{\max}} \right)$$

Lefebber (2003):

- Line of  $m$  identical queues:  $v(x,t) = \frac{\mu}{m + \rho(x,t)}$

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## Validation

- Line of 15 identical machines
- Infinite queues
- FIFO-policy
- Exponential Effective Processing Times
- Step-response (initially empty, start rate  $\lambda$ )
- Model 1, 2, 5 versus averaged discrete event

Rampup to 50% utilization (averaged discrete event)

Rampup to 50% utilization (validation studies)

Rampup to 25% utilization (validation studies)

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## Concluding remarks

Rampup to 50% with non-exponential arrivals ( $c_a^2 = 9$ )

- Correct steady state behavior
- Better description transient needed
- Second moment and correlation needs to be included

While keeping the following:

- No backward-flow allowed (cf. Daganzo '95)
- No negative density
- Stable steady states
  - i.e., constant feed rate  $\rightarrow$  equilibrium
  - also, equilibrium meets relations queueing theory

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## Control

- Number of machines  $n = 10$
- Mean processing time: 0.5h
- Desired  $u = 0.75$  (1.5 lot per h)
- Initial WIP  $x_i(0) = 0$

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## Nonlinear model

$$x_1(k+1) = x_1(k) - \frac{\mu x_1(k)}{1 + x_1(k)} + u(k)$$

$$x_2(k+1) = x_2(k) - \frac{\mu x_2(k)}{1 + x_2(k)} + \frac{\mu x_1(k)}{1 + x_1(k)}$$

$$\vdots$$

$$x_n(k+1) = x_n(k) - \frac{\mu x_n(k)}{1 + x_n(k)} + \frac{\mu x_{n-1}(k)}{1 + x_{n-1}(k)}$$

$$y(k) = \frac{\mu x_n(k)}{1 + x_n(k)}$$

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## MPC controller design

- Prediction horizon  $p = 100h$
- Control horizon  $p = 5h$
- Control constant over periods of 1h
- Time sampling: 40 steps per 1h

Cost function:

$$\min_u \sum_{i=0}^p \|y(k+i|k) - y_{\text{des}}\|_Q^2$$

Constraints:

$$0 \leq u(k) \leq 2 \quad 0 \leq \frac{\mu x_i(k)}{1 + x_i(k)} \leq 2$$

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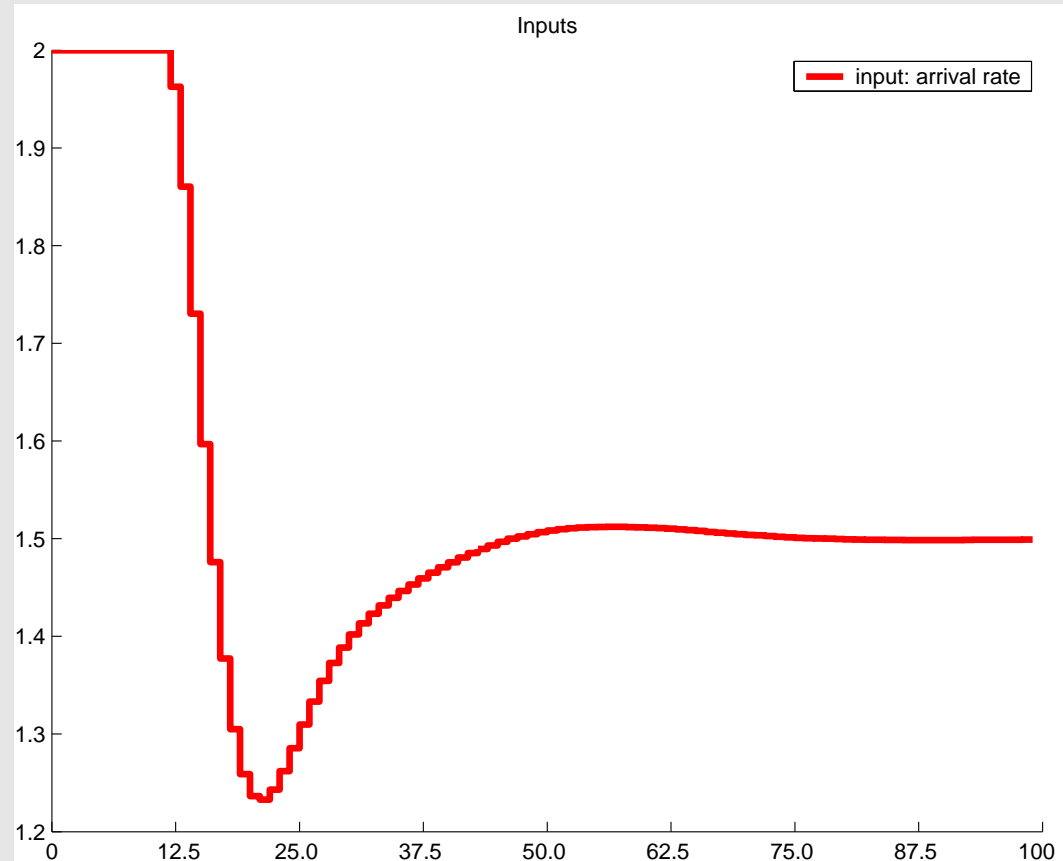
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## MPC based controller design





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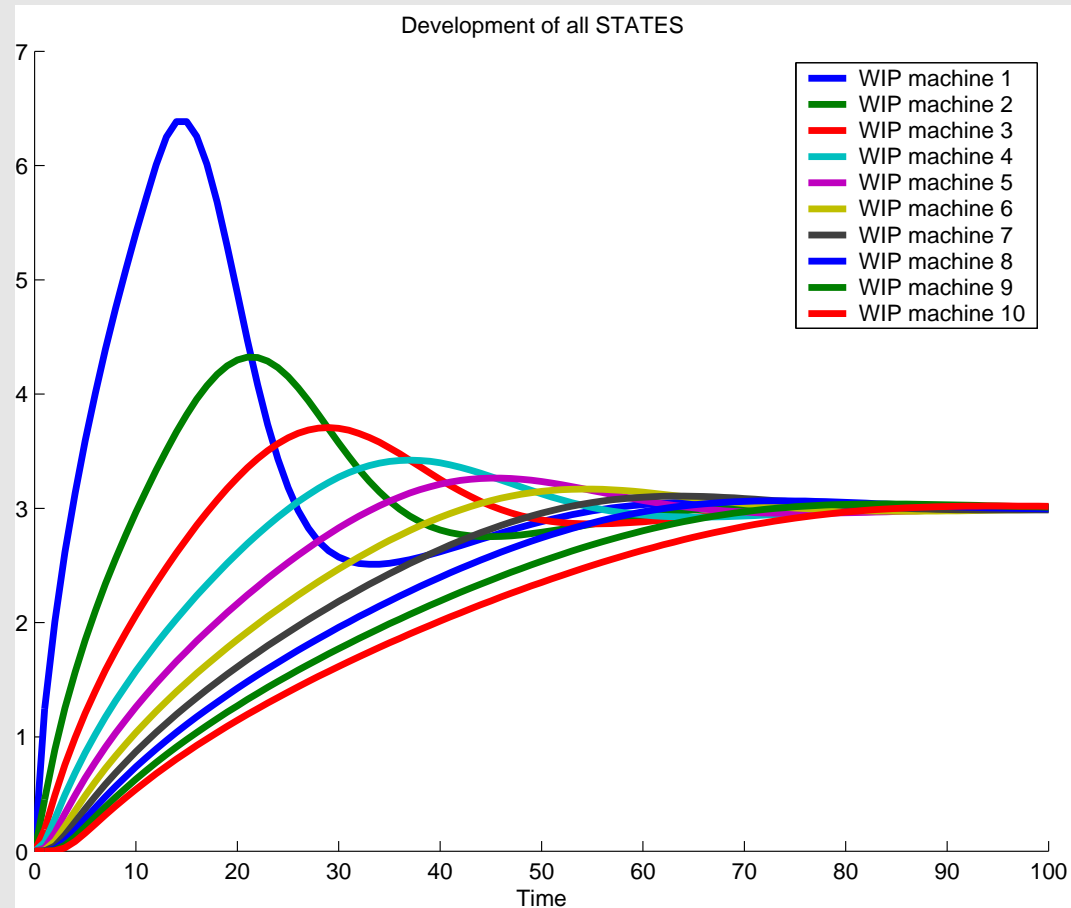
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## MPC based controller design



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## Conclusions

- Shown how to use  $\chi$  for building DE model.
- EPT can be used to get from real data to simple queueing network model
- Control framework
- Validation of PDE models
  - Transient needs improvement
  - Steady-state for changing variance
- MPC control seems promising